

Notice of References Cited

Application/Control No.

09/882,367

Applicant(s)/Patent Under

Reexamination

KIZILYALLI ET AL.

Examiner

Maria Guerrero

Art Unit

2822

Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,399,450	06-2002	Yu	438/300
	B	US-5,496,750	03-1996	Moslehi	438/297
	C	US-5,401,666	03-1995	Tsukamoto	438/305
	D	US-6,372,584	04-2002	Yu	438/300
	E	US-5,970,352	10-1999	Shiozawa et al.	438/300
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Kohno et al. "High Performance Poly-Si TFTs Fabricated Using Pulsed Lser Annealing and Remode Plasma CVD with Low Temperature Processing", February 1995, IEEE, pages 251-257.
	V	Robert C. Weast "CRC Handbook of Chemistry and Physics" , 1989-1990, pages F-73-F-74.
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.